

## Effect of Annealing Temperature on the performance of E-beam Evaporated TiO<sub>2</sub> Photoelectrode for the application of Perovskite Solar Cells

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**【Introduction】** Solid-state sensitized heterojunction solar cells are presently under intense investigation because they present a promising avenue towards cost-effective high efficiency solar power conversion [1]. These devices use molecular dye or semiconductors in form of quantum dots or extremely thin absorber layers as light harvesting agents. Perovskite (CH<sub>3</sub>NH<sub>3</sub>)PbI<sub>3</sub> nanocrystals have attracted attention as a new class of light harvesters for mesoscopic solar cells [2]. The aim of this work is to investigate the effect of annealing temperature on the performance of TiO<sub>2</sub> photoelectrode. The TiO<sub>2</sub> films have been deposited on ITO substrate by electron beam evaporation at room temperature. The properties of as-deposited (ASD) and annealed (ANN) TiO<sub>2</sub> films have been investigated and discussed.

**【Experimental】** The TiO<sub>2</sub> films were deposited on indium-doped tin oxide (ITO) substrate by Electron-beam evaporation system at room temperature [3]. After the chamber was evacuated to a background pressure below  $4 \times 10^{-6}$  Torr, The film thicknesses of all the TiO<sub>2</sub> films were around 150 nm measured by computer controlled crystal. Perovskite was layered on TiO<sub>2</sub> by spin-coating method. The  $\alpha$ -NPD and MoO<sub>3</sub> were used as hole-transport material. The prepared TiO<sub>2</sub> films were characterized by using X-ray diffractometer (XRD), UV/VIS spectrophotometer, field emission scanning electron microscope (FE-SEM). The active cell area was 0.38 cm<sup>2</sup>. The photovoltaic performances of DSCs were measured using a semiconductor parameter analyzer and solar simulator AM 1.5.

**【Results and discussions】** Figure 1(a) shows the  $(\alpha h\nu)^{1/2}$  versus photon energy curve which is draw by the help of Tauc formulae [4]; The ANN-TiO<sub>2</sub> shows the band gap  $E_g=2.25$  eV which is red-shifted from the ASD-TiO<sub>2</sub> film (3.33 eV), which may be due to crystal formation. From Fig. 1(b), ASD-TiO<sub>2</sub> shows fully amorphous structure where ANN-TiO<sub>2</sub> have high crystalline with rutile and anatase phases. The prepare TiO<sub>2</sub> has also strong perovskite peak.. The Fig. 1(c) displays the difference of absorbance spectrum which is defined as  $D = (\text{Absorbance of ANN-TiO}_2 \text{ films}) - (\text{Absorbance of ASD-TiO}_2 \text{ films})$ . It is cleared that the perovskite can absorb the light, so this electrode is very photo-active, Inset of Fig. 1(c1) shows the FESEM image of Perovskite layer on TiO<sub>2</sub> film, which is uniformly distributed whole the surface. Moreover solar cell assemblies by ANN-TiO<sub>2</sub> shows the better photovoltaic performance than the solar cell by the ASD-TiO<sub>2</sub> films.

**【Conclusion】** The TiO<sub>2</sub> films were successfully fabricated on ITO substrate by electron-beam evaporation system. The ANN-TiO<sub>2</sub> films had good crystallinity. The solar cell with ANN-TiO<sub>2</sub> films was showed good

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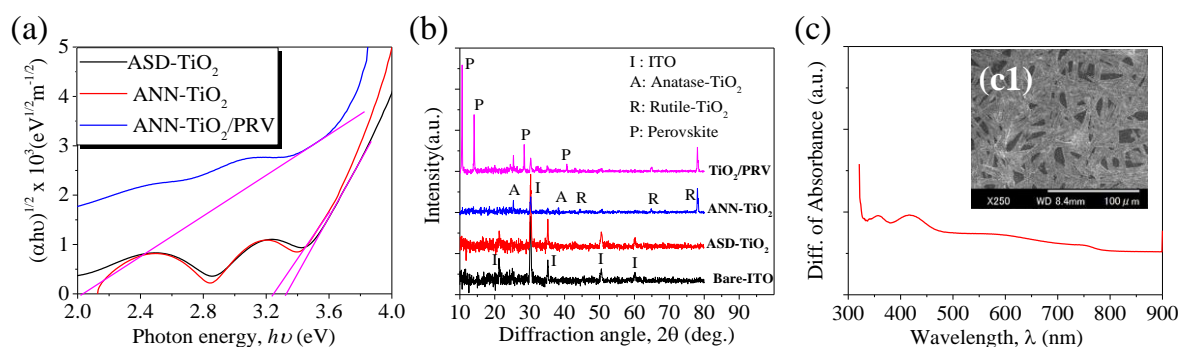


Fig. 1 (a)  $(\alpha h\nu)^{1/2}$  versus photon energy curve; (b) XRD pattern for TiO<sub>2</sub>/PRV, ANN-TiO<sub>2</sub>, ASD-TiO<sub>2</sub>, bare-ITO; and (c) Difference of absorbance spectrum, Inset (c1) SEM image of Perovskite layer on TiO<sub>2</sub> film.

### 【References】

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